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JUN 24 2004  
PATENT & TRADEMARK OFFICE  
Docket Number: 071469-0307558  
Client Reference: ES-038

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the Application of

FUMIHIKO HIGUCHI, et al.

Group Art Unit: 2822

Application No.: 10/812,347

Examiner:

Filed: March 30, 2004

Confirmation No.: 2682

For: Processing System and Method for Treating a Substrate

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This Information Disclosure Statement is being filed within three months of the U.S. filing date of this non-CPA application. No certification or fee is required.

This application is one of a series of related applications, identified in the attached Appendix, which are directed to related technical subject matter. The identification of those U.S. Patent Applications is not to be construed as a waiver of secrecy as to those applications now or upon issuance of the present application as a patent. The Examiner is respectfully requested to consider the cited applications and the art cited therein during examination.

Respectfully Submitted,



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Date: June 24, 2004

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APPENDIX

Examiner's Initials	First Inventor	Application No.	Filing Date	Enclosed
	HIGUCHI	10/812,347	3/30/04	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings

The Examiner's initials indicates he/she has considered the cited application relative to the subject application.

**DO NOT PRINT** the above information on the patent which results from the subject application.